

At page 9, lines 7-13, replace "Further, according to the present invention, the charged-particle-excluding means is disposed so as to cross the plasma and comprises a conductive member having at least one plasma-passing hole, to which voltage is applied. Furthermore, according to the present invention, the conductive member comprises a mesh-shaped or a grid-shaped conductive sheet." with

--Further, it is preferable to employ a pair of electrodes, which are disposed so as to be opposed and in parallel to each other, as said plasma generating electrodes. Alternatively, in addition to this pair of electrodes, it is possible to provide other electrodes.

Further, according to the present invention, in place of the electrodes that are disposed so as to interpose the plasma flow therebetween, a magnetic field, in which a line of magnetic force acts in a direction orthogonal to the plasma flow, may be provided in at least a part between the vicinity of the plasma vent and the vicinity of the substrate supporting table. In this case, the plus charged particles are moved by a force in a direction orthogonal to the plasma flow due to the line of magnetic force, so that the plus charged particles are excluded from the plasma flow. In the same way, the minus charged particles also receive a force in a direction opposite to the direction of the plus charged particles so that they move in a direction orthogonal to the plasma flow to be excluded from the plasma flow.

Furthermore, the present invention mainly comprises a surface treatment apparatus for generating plasma by plasma generating electrodes in a casing having plasma generating electrodes, a raw gas inlet and a substrate supporting table, plasma ionizing the raw gas and plasma processing a surface of the substrate, which is mounted on the substrate supporting table; wherein the casing is partitioned to two chambers, that is, a plasma generating chamber provided with the plasma generating electrodes and a substrate processing chamber provided with the substrate supporting table; the substrate processing chamber communicates with the plasma generating chamber through at least one plasma vent; and a conductive member applied with an electric voltage is provide at a part of the plasma vent.

Further, according to the present invention, it is preferable to employ a mesh-shaped or a grid-shaped conductive sheet for the conductive member."

Delete the paragraph at page 10, lines 9-18.

At page 11, lines 7-9, replace "conductive member, a pair of opposing electrodes, or the charged-particle-excluding means employing the line of magnetic force may be" with -- electrodes that are disposed so as to interpose the plasma flow therebetween or a magnetic field may be --.

At page 12, lines 20-22, delete "FIG. 1 is a schematic view of the surface treatment apparatus according to a first embodiment of the present invention."

At page 12, line 24, replace "second" with -- first --.

At page 13, line 2, replace "third" with -- second --.

At page 13, lines 5 and 6, replace "third" with -- second --.

At page 13, line 8, replace "fourth" with -- third --.

At page 13, line 11, replace "fifth" with -- fourth --.

At page 13, line 16, replace "sixth" with -- fifth --.

At page 13, line 21, replace "seventh" with -- sixth --.

At page 13, lines 24 and 25, replace "eighth" with -- seventh --.

At page 14, line 3, replace "eighth" with -- seventh --.

At page 14, lines 5 and 6, replace "ninth" with -- eighth --.

At page 14, lines 8 and 9, replace "tenth" with -- ninth --.

At page 14, lines 11 and 12, replace "eleventh" with -- tenth --.

At page 14, lines 14 and 15, replace "twelfth" with -- eleventh --.

At page 14, line 18, replace "twelfth" with -- eleventh --.

At page 14, lines 20 and 21 replace "thirteenth" with -- twelfth --.

At page 14, line 24, replace "thirteenth" with -- twelfth --.

At page 15, lines 1 and 2, replace "fourteenth" with -- thirteenth --.

At page 15, line 8, replace "FIG. 1" with --FIG. 2--.

At page 15, line 9, replace "1" with -- 11 --.

At page 15, line 10, replace "1" with -- 11--.

At page 16, line 9, replace "a cylindrical nozzle body 7" with -- a nozzle body 17 --.

At page 16, line 10, replace "7" with -- 17 --.

At page 16, line 16, replace "7" with -- 17 --.

At page 17, lines 9-12, replace "a conductive sheet 9 in a mesh shape is attached on the substrate supporting table 8 via supporting columns 8b, each of which is composed of an insulating material." with "the nozzle body 17, which is attached to the plasma vent 6, has a circular section and a circular truncated cone shape whose diameter expands from a plasma generating chamber 3 toward a substrate processing chamber 4. A mesh-shaped conductive sheet 9, which is connected to a direct current power supply DC, is attached to an end face of this nozzle body 17 on a side toward the substrate processing chamber 4 through an insulating material 17a."

Delete the text starting at page 20, line 2 through page 21, line 15 ending with "substrate S can be efficiently prevented."

At page 21, line 16, replace "second" with -- present --.

At page 22, after line 3, insert the paragraph:

-- The other embodiments and modified examples according to the present invention will be specifically described with reference to the drawings below. In the following description, the same components as those of the above first embodiment are provided with the same reference numerals as those of the first embodiment and their detail descriptions will be omitted. --

At page 22, line 5, replace "third" with -- second --.

At page 22, line 9, replace "second" with -- first --.

At page 22, line 24, replace "fourth" with -- third --.

At page 23, line 13, replace "fifth" with -- fourth --.

At page 24, line 13, replace "sixth" with -- fifth --.

At page 25, line 10, replace "seventh" with -- sixth --.

At page 26, line 21, replace "seventh" with -- sixth --.

At page 26, line 21, delete "7,".

At page 26, after line 21, insert -- each --.

At page 26, line 22, delete "a cylindrical shape or".

At page 26, line 23, after "possible to use", insert -- a cylindrical nozzle or --.

At page 27, line 10, replace "an eighth" with -- a seventh --.

At page 28, line 12, replace "eighth" with -- seventh --.

At page 28, line 24, replace "a ninth" with -- an eighth --.

At page 29, line 16, replace "tenth" with -- ninth --.

At page 30, line 12, replace "ninth and tenth" with -- eighth and ninth --.

At page 30, line 14, replace "eighth" with -- seventh --.

At page 30, line 25, replace "an eleventh" with -- a tenth --.

At page 31, line 16, replace "a twelfth" with -- an eleventh --.

At page 31, line 20, delete "3".

At page 31, line 20, delete "4".

At page 34, line 1, replace "twelfth" with -- eleventh --.

At page 35, line 4, replace "thirteenth" with -- twelfth --.

At page 35, line 14, replace "fourteenth" with -- thirteenth --.

IN THE CLAIMS

Please amend Claims 1-3 as follows:

1. A surface treatment apparatus for generating plasma by [a pair of] plasma generating electrodes in a casing having [said pair of] plasma generating electrodes, a raw-gas inlet and a substrate supporting table, plasma ionizing the raw gas and plasma processing a surface of said substrate, which is mounted on said substrate supporting table; characterized in that

said casing is partitioned to two chambers, that is, a plasma generating chamber provided with said plasma generating electrodes and a substrate processing chamber provided with said substrate supporting table;

said substrate processing chamber communicates with said plasma generating chamber through at least one plasma vent; and